



## Discovery of nanoscale reduced surfaces and interfaces in VO<sub>2</sub> thin films as a unique case of prewetting

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Received 7 January 2014; revised 20 January 2014; accepted 24 January 2014

Available online 31 January 2014

VO<sub>2</sub> thin films grown on SiO<sub>x</sub>/Si substrates have been characterized at the sub-nanometer level by Cs-corrected scanning transmission electron microscopy along with electron energy loss spectroscopy. Reduced transitional regions of 2–3 nm thick were found at both the surface and the interface, where the vanadium valence progressively changes from +4 to +2. The formation of these nanometer-thick surficial and interfacial layers can be interpreted as a unique case of prewetting, and it explains the degradation of metal-to-insulator transition properties in VO<sub>2</sub> thin films.

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**Keywords:** VO<sub>2</sub> thin film; Prewetting; Electron energy loss spectroscopy (EELS); Surface structure; Interface structure

VO<sub>2</sub> exhibits a metal-to-insulator transition (MIT) near room-temperature (68 °C), which causes dramatic changes in both electrical and optical properties [1]. During this transition, the crystal structure of VO<sub>2</sub> transforms from the high-temperature tetragonal rutile phase (*P4<sub>2</sub>/mmm*) into the low-temperature monoclinic phase (*P2<sub>1</sub>/c*) [2–4]. This transition can be used for various applications, such as thermochromic “smart window” coatings [5,6], memory devices [7,8] and ultrafast switches [9–11]. The binary vanadium–oxygen system consists of four primary oxide phases – VO, V<sub>2</sub>O<sub>3</sub>, VO<sub>2</sub> and V<sub>2</sub>O<sub>5</sub> – as well as two series of the homologous mixed-valence oxides known as the Wadsley (V<sub>2n</sub>O<sub>5n–1</sub>) and Magnéli phases (V<sub>n</sub>O<sub>2n–1</sub>) [12,13]. These competing phases can be formed during the film deposition process, and can broaden the phase transition,

reduce the transition amplitude, and lower the transition temperature [13,14]. Thus, maintaining the stoichiometric VO<sub>2</sub> single phase is crucial. Moreover, surfaces and interfaces in VO<sub>2</sub> can introduce chemical inhomogeneity to affect the MIT behavior. By using atomic resolution electron energy-loss spectroscopy (EELS) analysis, an interfacial V<sub>2</sub>O<sub>3</sub>-like transition layer was revealed in a well-crystallized VO<sub>2</sub> film grown epitaxially on a sapphire substrate [15]. The determination of the V oxidation states is largely owing to the EELS near-edge structures, which are very sensitive to the chemical environments [15–17]. This study is motivated by the critical need to perform a structural and chemical characterization of VO<sub>2</sub> film deposited on silicon substrate, which is technically more useful than the previous study on the VO<sub>2</sub>/sapphire for understanding the MIT properties.

In this study, a single-phase VO<sub>2</sub> film deposited on such a SiO<sub>x</sub>/Si substrate was investigated by bright-field (BF) imaging, high-angle annular dark-field (HAADF) imaging and EELS analysis in a Cs-corrected scanning

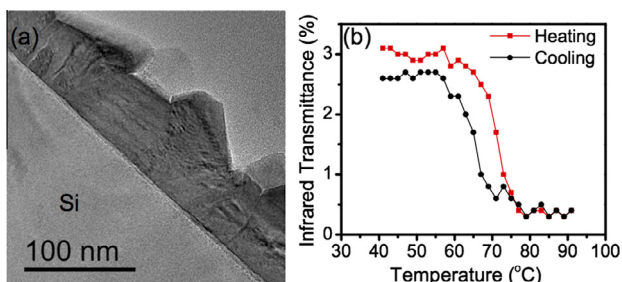
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transition electron microscope (STEM). Transition layers of 2–3 nm thick with continuous reduction are found at both the surface and the interface, the formation of which can be explained as a unique case of prewetting using a modified Cahn diffuse-interface model [18].

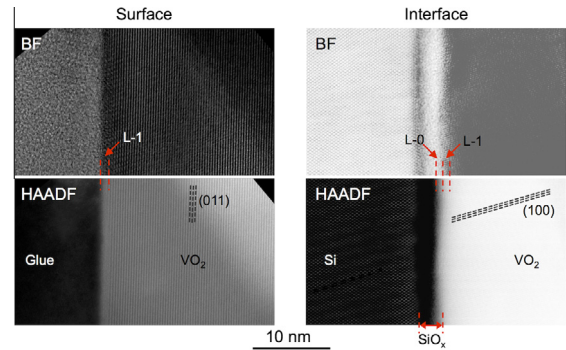
The VO<sub>2</sub> film was deposited by reactive magnetron sputtering on the Si substrate with a ~3 nm thick amorphous native oxide (SiO<sub>x</sub>) layer on the top of it (SiO<sub>x</sub>/Si). A pure V sputtering target was used while the Ar and O<sub>2</sub> gases were introduced with the required flow ratio of 2.7% for O<sub>2</sub> (O<sub>2</sub> flow rate/total flow rate). The substrate temperature was maintained at 450 °C during the film growth for 200 min [19]. The VO<sub>2</sub> thin film is about 100 nm thick and composed of irregularly shaped grains from around 10 nm to 100 nm without epitaxial relation to the substrate, as seen in Figure 1a. The MIT properties were investigated by measuring the infrared transmittance ( $\lambda = 2000$  nm) as a function of temperature on a UV–vis–NIR spectrophotometer (Hitachi U-4100, Japan). As shown in Figure 1b, the transition temperature is around 68 °C and comparable to that of VO<sub>2</sub> single crystal. However, the hysteresis width ( $\Delta H$ ) is about 6 °C and the transition sharpness ( $\Delta T$ ) is about 16 °C, which are wider than those of a VO<sub>2</sub> single crystal ( $\Delta H \sim 2$  °C and  $\Delta T \sim 0.1$  °C).

The cross-section TEM specimens were prepared by standard mechanical polishing and ion milling. The local structural and chemical investigations were performed in a Cs-corrected STEM (USTEM-200, Nion Co., USA), operated at 100 keV to minimize the beam damage. In HAADF images, V atoms exhibit enhanced intensity as compared with Si atoms. EELS spectrum images are obtained using a sub-angstrom electron probe, with a typical dwelling time of 0.3 s per pixel and an energy dispersion about 0.06 eV per channel. The optimized pixel size is 0.15 nm, which enables relatively fast acquisition.

Transition layers are found at both the surface and the interface of the single-phase, polycrystalline VO<sub>2</sub> film on SiO<sub>x</sub>/Si substrate, as shown in Figure 2. At a typical faceted grain surface, the first 1.0–1.5 nm thick layer (denoted as L-1 in the following text) is observed to be structurally different from the grain interior in the BF image, which is further confirmed in the HAADF image by the absence of transgranular lattice fringes within this layer (the absence may be caused by either a poorer crystalline form, a smaller fringe spacing or lattice misalignment). The interface between the VO<sub>2</sub> grains and the ~3 nm thick amorphous SiO<sub>x</sub> layer exhibits more structural variations, a typical case also



**Figure 1.** (a) TEM image and (b) thermal hysteresis loops of the infrared transmittance at wavelength 2000 nm for VO<sub>2</sub> thin film.



**Figure 2.** BF and HAADF images for the surface (left) and interface (right) of the VO<sub>2</sub> thin film. The fringes are indexed referring to the VO<sub>2</sub> monoclinic phase.

appearing in Figure 2. By comparing the simultaneously recorded BF and HAADF images, V-related contrast was found to extend beyond the edge of the VO<sub>2</sub> grain by about 1.0–1.5 nm into the amorphous SiO<sub>x</sub>, indicating a significant diffusion of V ions into the SiO<sub>x</sub> layer (denoted as L-0). Adjacent to this diffuse layer is a transition layer, again 1.0–1.5 nm thick (L-1), showing lattice fringes in the BF image but not in the HAADF image, which is similar to the surface transition layer.

Spatially resolved EELS reveals the local chemical characteristics of these extended transition layers on the VO<sub>2</sub> film, thanks to the strong hybridization of vanadium unfilled 3d bands with oxygen 2p bands, which induces significant changes on the V-L<sub>2,3</sub> white lines located at 515 and 522 eV. From V<sub>2</sub>O<sub>5</sub>, VO<sub>2</sub> and V<sub>2</sub>O<sub>3</sub> to VO, successive chemical shifts of around 0.2, 1.2 and 0.6 eV on the V-L<sub>2,3</sub> lines towards lower energies indicate the successive reductions of the valence state [15–17]. Furthermore, a clear shoulder is visible on the V-L<sub>3</sub> edge for the VO<sub>2</sub> phase. On the other hand, the O2p–V3d hybridization causes the transition of O1s electrons to the vacant anti-bonding t<sub>2g</sub> and e<sub>g</sub> states in the VO<sub>6</sub> octahedral environment, which correspond to the pre-peaks of the O-K edge at around 530 eV, thus also reflecting the change in V valence [20,21]. With the decreasing oxidation state of V, the 3d electrons tend to preferentially fill the t<sub>2g</sub> lower state, which lowers the relative weight of unoccupied t<sub>2g</sub>/e<sub>g</sub> and gives rise to the characteristic O-K features: two well separated peaks for VO<sub>2</sub>; overlapping but still recognizable for V<sub>2</sub>O<sub>3</sub> and V<sub>2</sub>O<sub>5</sub>; and overlapping into one broad peak for VO. Therefore, such fine structures of the V-L<sub>2,3</sub> and the adjacent O-K edges can be used to monitor the local chemical change and the non-stoichiometry distribution in the VO<sub>2</sub> film.

EELS spectrum imaging is performed across these transition layers of this VO<sub>2</sub> film, as shown in Figure 3(a–d) for the surface and e–h for the interface). HAADF images acquired synchronously are also shown as references (Fig. 3a and e). The energy shift maps (Fig. 3b and f) are extracted from the maximum of the V-L<sub>3</sub> line at each pixel, with the energy position for VO<sub>2</sub> being set to zero; drifting during acquisition to the right-hand side is also detected. Across both the surface and interface, the energy shift decreases continuously towards VO<sub>2</sub> over a width of 3 nm or more,

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